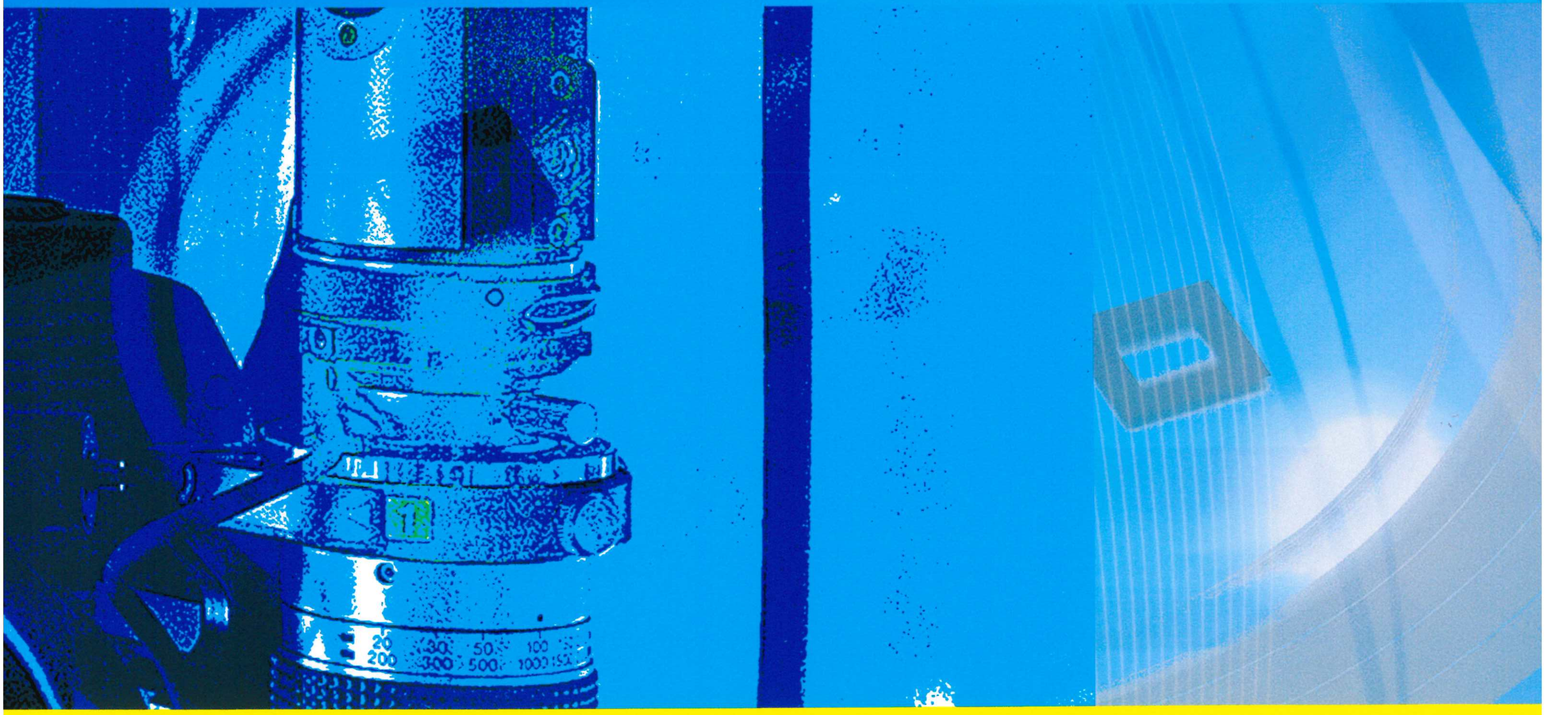
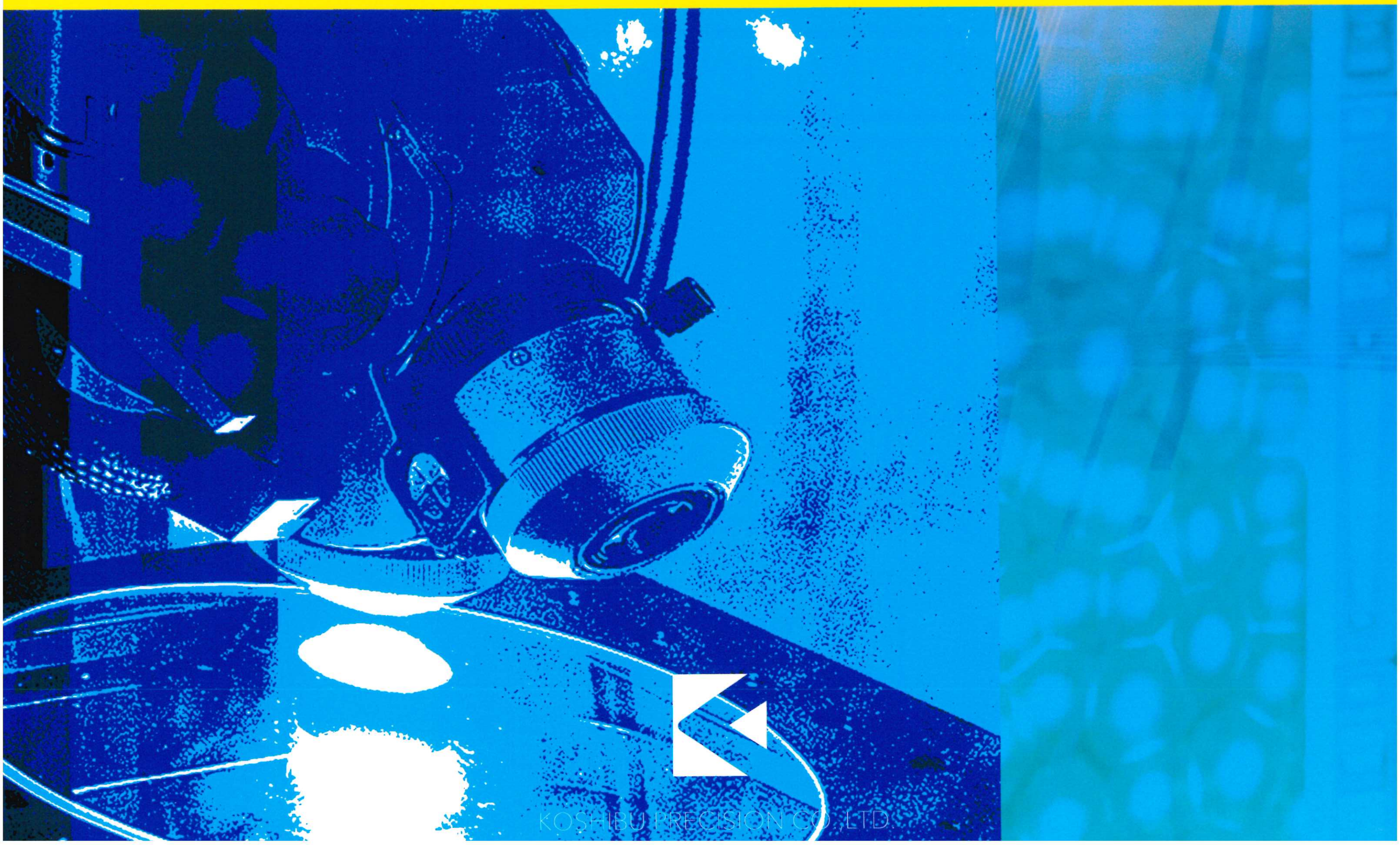


EXPERT IN THE NANO WORLD

Located amid the abundant nature between the grand mountain ranges bracketing the Ina Valley, we have adopted the slogan "Experts in the Nano World" . We continuously and actively strive to create and implement new techniques. We aim to "Produce better products with an emphasis on Quality First" in order to increase the high levels of satisfaction and faith that we have achieved among our customers.



Name

Koshibu Precision Co., Ltd.

Location

Tokyo Headquarters
〒179-0085 Tokyo-to Nerima-ku Hayamiya 2-20-11
TEL.03-3934-2670 FAX.03-3931-6550
Nagano Factory
〒399-3303 Nagano-ken Shimoina-gun Matsukawa Town, Moto-Ohshima 2903-33
TEL.0265-36-3400 FAX.0265-36-5237

Capital

¥50 million

Founded

July, 1964

President Taiichi Ogihara

Main Line of Products

Rotary Encoder Slit Disks
Glass Photomasks (2D ／ 3D)
Various Optical Scales / Reticles
Optical parts including Lenses, Prisms, Mirrors, etc.

Company History

1964
Founded the company as Ogihara Optical Scale Laboratory in Toshima Ward, Tokyo
1967
Moved to Nerima Ward in Tokyo
Changed the name to Ogihara Optical Scale Laboratory Incorporated.
1974
Changed the company name to Koshibu Precision Inc.
1978
Changed to Koshibu Precision Co., Ltd.
1985
Expanded the factory
Developed the Circle-division Pattern Generator
2002
Acquired the 200×200 Laser Direct Write Pattern Generator
2005
Acquired the 400×400 Laser Direct Write Pattern Generator
2010
Expanded the glass-processing equipment / factory
Stepper (reduction projection aligner) acquired
Acquired the Full automated Core Drill Machine (Currently 12 units)
Acquired the Inner and outer diameter Automatic Chamferin Machineg (Currently 12 units)
Acquired the Glass substrate RCA Washing Device
＊Stepper (reduction projection aligner) acquired (Unit 1)
2011
Stepper (reduction projection aligner) acquired
Acquired the 200×200 Laser Direct Write Pattern Generator (3D Gray scale mask compatible)
Sputtering device (inline method) acquired
2012
3D Gray scale mask measuring laser microscope acquired
Acquired an Automatic External Appearance Inspection Apparatus (encoder)
2013
Acquired a projection exposure device (1/1 stepper)
2016
Acquired dry etching device (Unit 1)
2017
Acquired Laser lithography system with automatic substrate feed
2019
Acquired a fully-automated dicer (Currently 12 machines)
2020
Acquired 400×400 Laser lithography system (for 3D grayscale masks)
2021
Built and began operation of the main factory
Acquired Stepper (reduction projection aligner) (Unit 3)
Acquired dry etching device (Unit 2)